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Stefan Kaierle
Stefan W. Heinemann
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Contents

v *Authors*
vii *Conference Committee*

LASE PLENARY SESSION

10525 02 **Advanced industrial laser systems and applications (Plenary Paper)** [10525-203]

SESSION 1 SYSTEMS I

10525 03 **The Laser Megajoule facility: laser performances and comparison with computational simulation** [10525-1]

10525 04 **Multi-physical modeling of thermal and dispersive effects in optical systems for high power ultra-short laser pulses** [10525-2]

10525 05 **Tuneable UV solid-state laser lines for surface processing** [10525-3]

10525 06 **Influence of thermally induced aberrations on resulting intensity distribution** [10525-4]

10525 07 **Beam shaping of focused radiation of multimode lasers** [10525-5]

SESSION 2 SYSTEMS II

10525 08 **Improving accuracy of robot-guided 3D laser surface processing by workpiece measurement in a blink** [10525-6]

10525 09 **Mobile laser cutting system for complex rescue operations** [10525-7]

10525 0A **Ball-shaped end caps for fiber laser systems** [10525-8]

10525 0B **Measurement of the dispersion properties of large aperture mirrors at arbitrary incidence angle and polarization state** [10525-9]

SESSION 3 WELDING AND CUTTING

10525 0C **BrightLine weld-spatter reduced high speed welding with disk lasers** [10525-11]

10525 0D **Pores in laser beam welding: generation mechanism and impact on the melt flow** [10525-12]

10525 0E **New welding techniques and laser sources for battery welding** [10525-13]

10525 0F New milestones in laser cutting for quality improvement and process automation [10525-26]

SESSION 4 SURFACE TREATMENT I

10525 0G Research on inorganic cladding of neodymium phosphate glass in slab amplifier [10525-15]

10525 0H Backscattered light properties during femtosecond laser ablation and development of a dynamic interferometric focusing system [10525-16]

10525 0I Laser beam ablation of thick steel plates without affecting the material underneath [10525-17]

10525 0J Femtosecond pulsed laser deposition of a boron thin film aiming at the development of a low-cost neutron detector [10525-18]

10525 0L Approaches for increasing process rate of local 3D laser decoating for series production of hybrid composites [10525-20]

SESSION 5 SURFACE TREATMENT II

10525 0M Influence of operating parameters on morphology of laser hardened surfaces [10525-22]

10525 0N Development of high power laser ablation process for polycrystalline diamond polishing: Part 1. Fundamental understanding of PCD ultra-short pulsed laser ablation [10525-23]

10525 0O High pulse energy kW average power nanosecond lasers enable breakthrough in rapid coating removal [10525-24]

Authors

Numbers in the index correspond to the last two digits of the seven-digit citation identifier (CID) article numbering system used in Proceedings of SPIE. The first five digits reflect the volume number. Base 36 numbering is employed for the last two digits and indicates the order of articles within the volume. Numbers start with 00, 01, 02, 03, 04, 05, 06, 07, 08, 09, 0A, 0B...0Z, followed by 10-1Z, 20-2Z, etc.

Airiau, J.-P., 03
Amaral, Marcello Magri, 0H
Beau, V., 03
Berger, Peter, 0D
Bonhoff, Tobias, 04
Bordenave, E., 03
Borzsonyi, A., 0B
Brodesser, Alexander, 09
Chard, Simon, 0O
Chies, T., 03
Costa, Priscila, 0J
Dai, DeChang, 0O
Denis, V., 03
De Pretto, Lucas, 0H
Dold, Eva, 0E
Emonts, Michael, 08, 0L
Faisst, Birgit, 0E
Fetzer, Florian, 0D
Feuchtenbeiner, S., 0C
Fischer, Kai, 08, 0L
Freitas, Anderson Zanardi, 0H
Frühauf, Boris, 08
Gabzdyl, Jack, 0E
Gaussmann, Fabian, 05
Genezini, Frederico Antônio, 0J
Graf, Thomas, 0D
Grafe, Robert, 09
Grimm, Vyacheslav, 05
Haug, P., 0C
Havrilla, D., 0C
Hennigs, Christian, 09
Hermsdorf, J., 0I
Hesse, Tim, 0C, 0E
Heyrick, Jan, 0F
Hoff, C., 0I
Holtz, Ronald, 0N
Hu, Haoyue, 0D
Hustedt, Michael, 09
Ivanenko, Mikhail, 05
Julien, X., 03
Kaierle, Stefan, 09, 0I
Kaiser, Elke, 0E
Kalis, Henning, 05
Kirchhoff, Marc, 0E
Kogel-Hollacher, Markus, 0F
Kovacs, M., 0B
Kwon, Young Key, 0O
Lacampagne, L., 03
Lacombe, C., 03
Laffir, Fathima, 0N
Laskin, Alexander, 06, 07
Laskin, Vadim, 06, 07
Li, Haiyuan, 0G
Li, Yangshuai, 0G
Loosen, Peter, 04
Machado, Noé Gabriel Pinheiro, 0J
Maharjan, Niroj, 0M
McComb, Timothy S., 0O
Metsios, Ioannis, 0O
Moser, Rüdiger, 08
Ostrun, Aleksei, 06, 07
Overmeyer, L., 0I
Pantsar, Henrikki, 0E
Raele, Marcus Paulo, 0H, 0J
Rudolf, Andreas, 0F
Samad, Ricardo Elgul, 0H, 0J
Scalbert, William, 0N
Schaefer, M., 02
Schares, Richard, 08, 0L
Schmidt, B., 02
Schmitt, Stefan, 08, 0L
Seres, I., 0B
Sipos, A., 0B
Somoskoi, T., 0B
Sozet, M., 03
Speker, N., 0C
Stollenwerk, Jochen, 04
Tanner, David, 0N
Vermersch, S., 03
Vieira, Nilson Dias, Jr., 0H, 0J
Volpp, Joerg, 07
Wang, Bingyan, 0G
Weber, Rudolf, 0D
Wetter, Niklaus U., 0H
Wiesner, Markus, 05
Wu, Naien, 0M
Xiong, Huai, 0G
Zhang, Yanli, 0G
Zheng, Wenxin, 0A
Zhou, Shenlei, 0G
Zhou, Wei, 0M
Zhou, Yu, 0M
Zhu, Gongwen, 0A
Zhu, Jianqiang, 0G

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